

# A review and outlook for the removal of radon-generated $^{210}\text{Po}$ surface contamination

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# Motivation

Exposure to radon gas leaves behind progeny on surfaces.

$^{210}\text{Pb}$  is long lived

$^{210}\text{Po}$  is an alpha emitter

A problem for all low background, rare event searches

Degraded alpha can fall into  $0\nu\beta\beta$  region of interest

Nuclear recoils and  $(\alpha,n)$  a problem for dark matter detectors

All low background experiments study this background

Exposure to radon gas leaves behind Rn progeny

The short-lived portion of the radon decay chain deposit on a surface

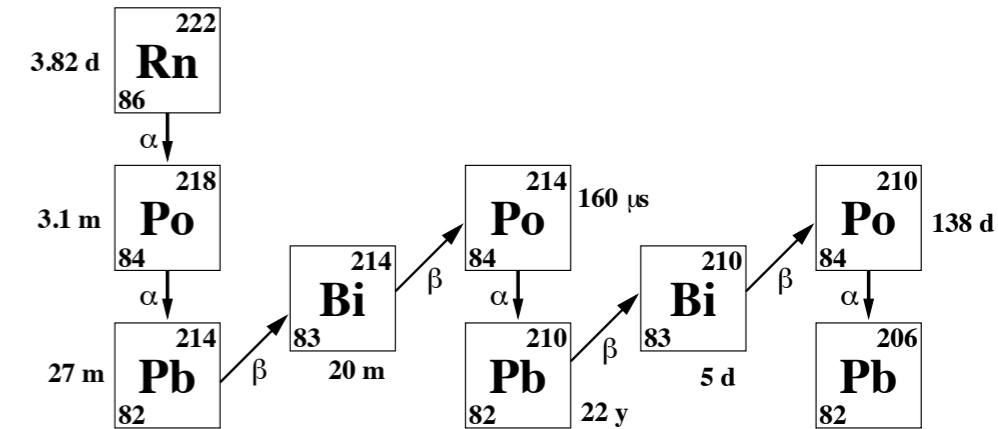
$^{218}\text{Po}$  and  $^{214}\text{Po}$  alpha decays can recoil the daughter nuclei deeper into a material surface

An implanted distribution of  $^{210}\text{Pb}$  down to  $0.05 - 0.1 \mu\text{m}$

Radon gas can diffuse into the material during exposure

Contribution depends on the material (plastics vs metals)

Progeny are then deposited deeper into the subsurface



# Motivation

The deposition of Rn progeny continues to be modeled and studied  
Evaluation of cleaning and surface removal of Rn progeny is on going

Some of the past LRT proceedings articles that focus solely on deposition or removal of Rn progeny

## LRT 2015

M. Bruemmer et al AIP Conf. Proc 1672 , 140005 (2015)

G. Zuzel et al AIP Conf. Proc 1672, 150002 (2015)

K. Kobayashi AIP Conf. Proc 1672, 050003 (2015)

## LRT 2013

L. Pattavina AIP Conf. Proc 1549, 82 (2013)

R. W. Schnee et al. AIP Conf. Proc 1549, 128 (2013)

G. Perumpilly et al. AIP Conf. Proc 1549, 239 (2013)

C. Jillings AIP Conf. Proc 1549, 86 (2013)

## LRT 2010

V. E. Guiseppe et al. AIP Conf. Proc 1338, 95 (2011)

M. Wójcik et al. AIP Conf. Proc 1338, 224 (2011)

## LRT 2006

M. Wójcik et al AIP Conf. Proc 897, 53 (2007)

## LRT 2004

M. Leung AIP Conf. Proc 785, 184 (2005)

... and more studies published elsewhere or in experiment overview papers

# Po Cleaning

Findings from studies evaluating cleaning and surface removal techniques:

Pb and Bi generally removed easily using a variety of standard methods

Po has been more difficult to remove - more aggressive techniques recommended

Next generation experiments will have more parts with greater surface contamination control requirements.

Cleaning requirements and considerations:

Efficient in removing Rn progeny, specifically  $^{210}\text{Po}$

Quantities and purity of chemicals needed

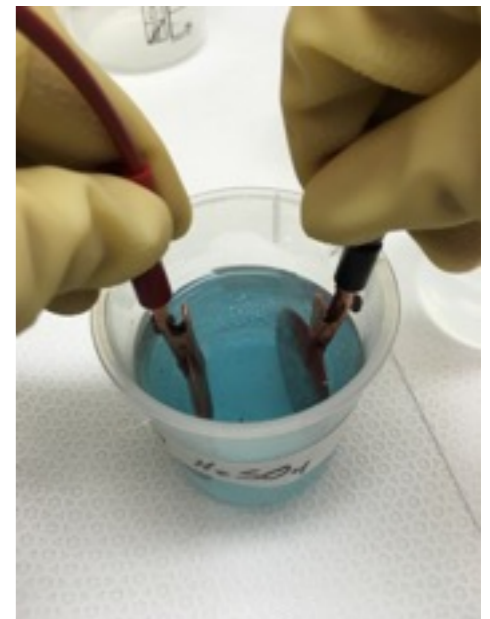
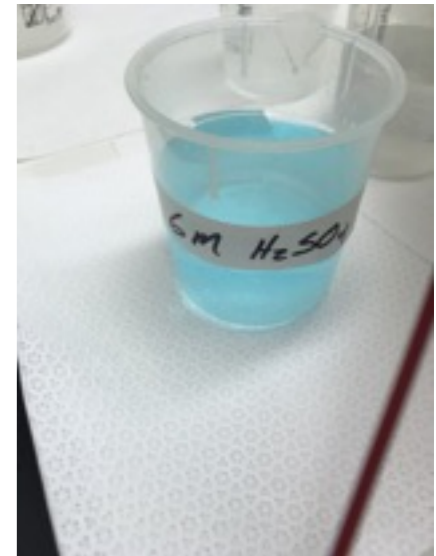
Chemical waste

Generation of chemical fumes

Underground operation limitations

Number of parts and process automation

Maintain dimensional and mechanical tolerances



# Po Surface Location

If  $^{210}\text{Po}$  resides directly on a surface, the emitted alpha would be detected at its full energy

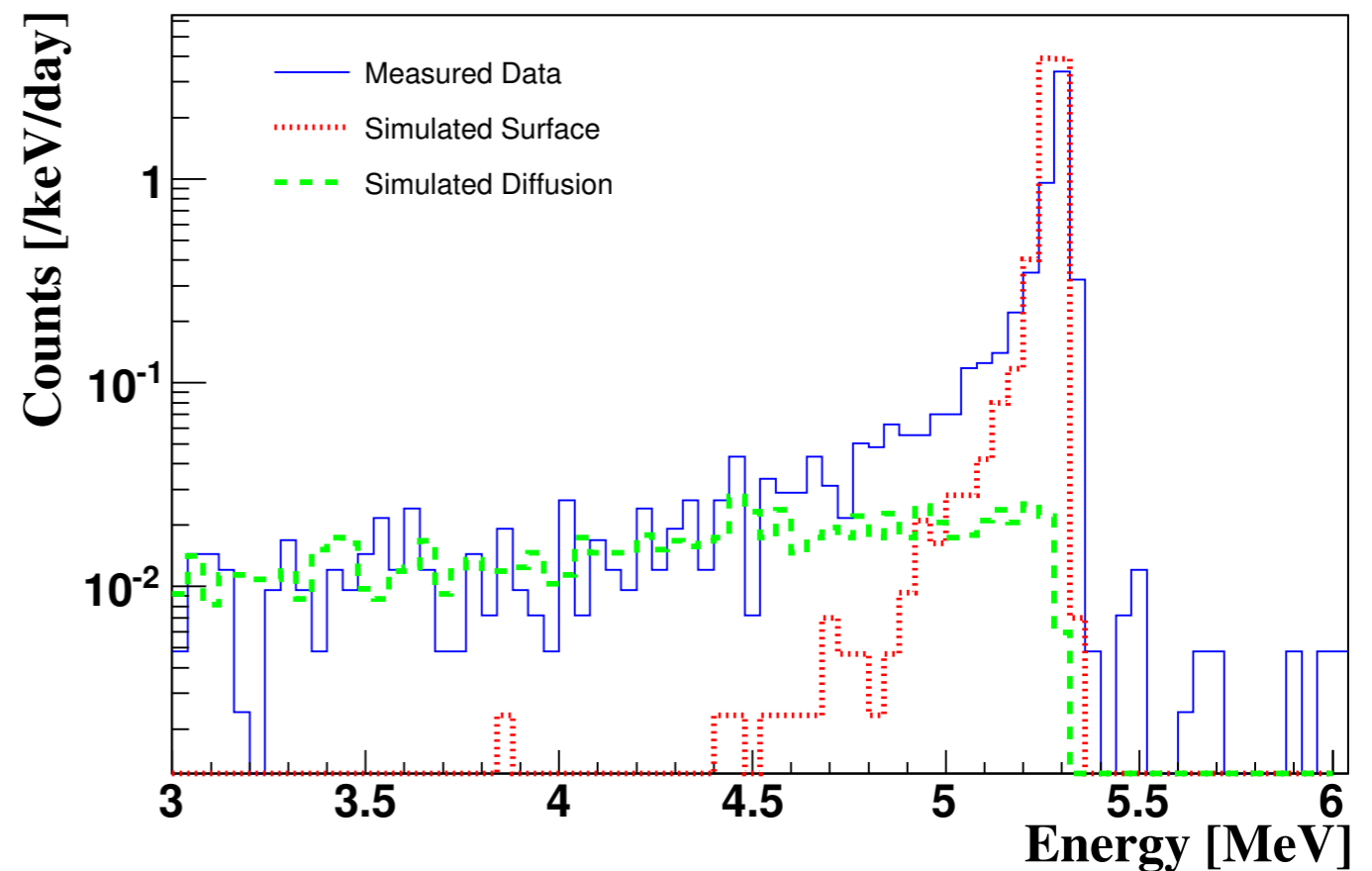
For Rn-exposed surfaces, the alpha energy is degraded due to:

Surface roughness affects the amount of degradation due to the extra material an alpha must penetrate

Bulk or diffused contamination

Stainless steel example

Simulation includes an effective roughness parameter (red) and deeper (green) contributions



G. Perumpilly et al. AIP Conf. Proc 1549, 239 (2013)

The range of a 5 MeV alpha is  $\sim 20 \mu\text{m}$  in metals

You would expect that cleaning of surfaces would easily remove the majority of Po atoms implanted within  $0.05 - 0.1 \mu\text{m}$

# Po Removal Techniques

Surface cleaning techniques have been evaluated with varying results

E.W. Hoppe et. al [NIM A579 (2007) 486]

## Nitric Etch of Cu

Very effective at removing all surface contaminants

Not the most practical for a controlled process

PNNL method:  $H_2SO_4$  and  $H_2O_2$

Shows promise for  $^{210}Po$  removal

Some concern with Po solubility

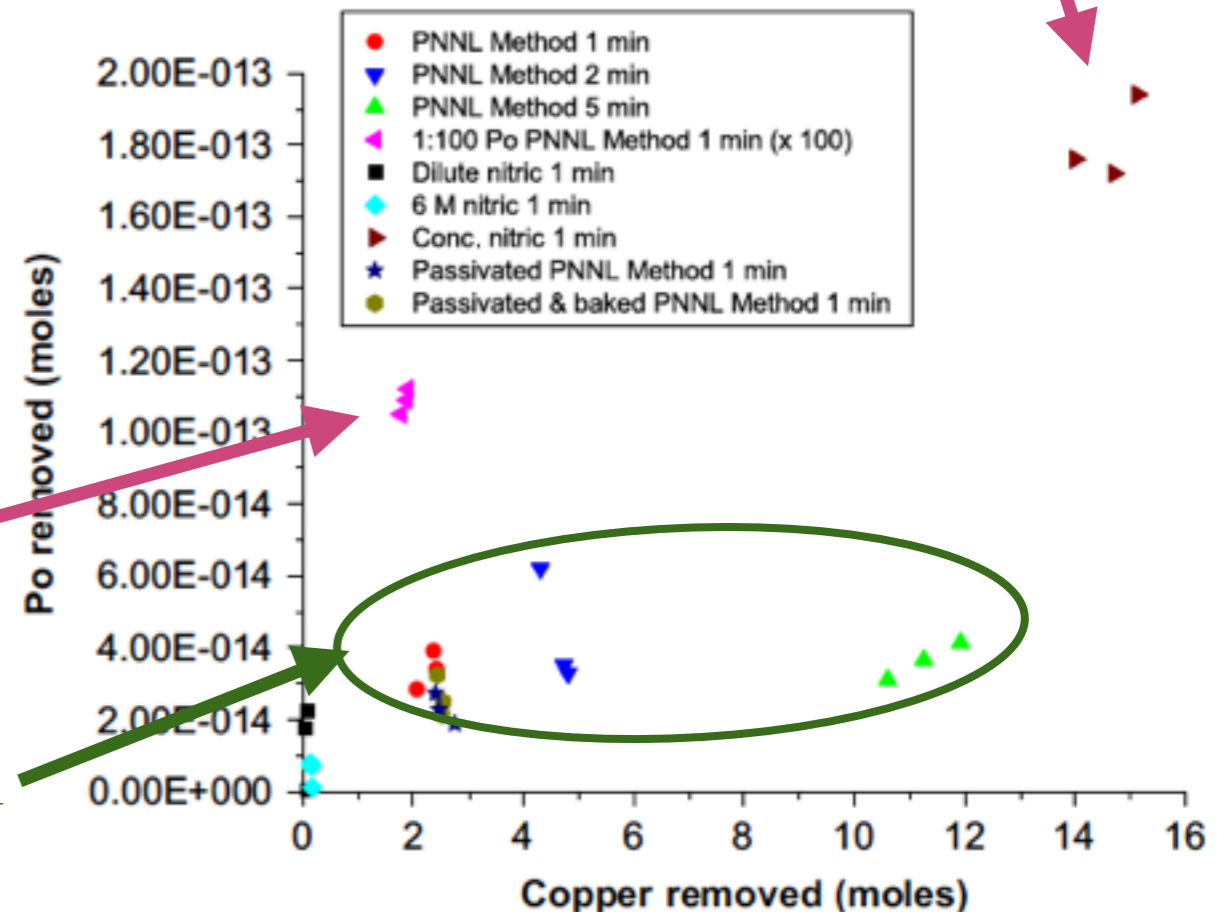
Method works for removing surface U/Th

(see previous talk by C. Christofferson for MAJORANA experience)

Improved Po removal with lower Po concentration

Limited Po removal

Nitric most effective



# Po Removal Techniques

G. Zuzel *et al.* [AIP Conf. Proc. **1672** (2015) 150002] + several other papers

Etching: Cu by PNNL method; Steel by HNO<sub>3</sub>+HF; Ge by CP4

Greater reduction of Po in Steel and Ge than in Cu

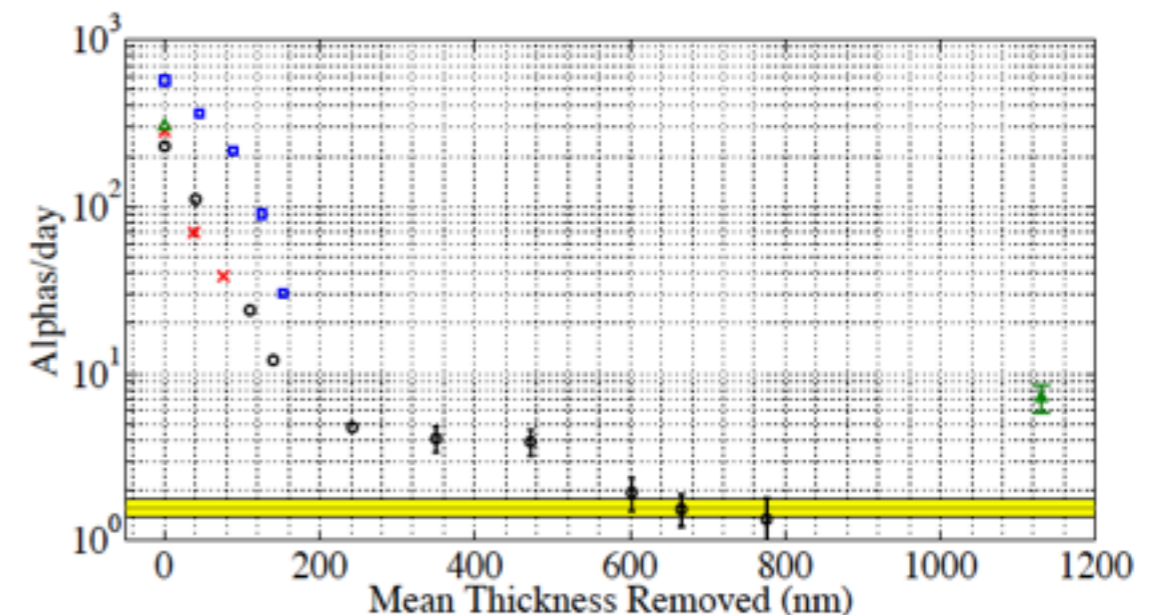
Electropolishing: Cu: H<sub>3</sub>PO<sub>4</sub> + 1-butanol + ΔV; Steel H<sub>3</sub>PO<sub>4</sub> + H<sub>2</sub>SO<sub>4</sub> + CrO<sub>3</sub> + ΔV

More efficient reduction, especially for Po

Isotope	Activity reduction factors after etching / electro-polishing			
	Copper	Stainless steel	Germanium	
			NPGe	HPGe
<sup>210</sup> Pb	50 / 300	100 / 400	100	700
<sup>210</sup> Bi	50 / 300	100 / 800	400	800
<sup>210</sup> Po	1 / 400	20 / 700	1000	100

R. Schnee *et al* [AIP Conf. Proc. **1549** (2013) 128]

Electropolishing steel: H<sub>3</sub>PO<sub>4</sub> + H<sub>2</sub>SO<sub>4</sub> @ 2.4 V



# Po Chemical Behavior

Why the mixed results for surface  $^{210}\text{Po}$  removal?

All methods use an acidic solution

Po (neutral) can exist in solution over the entire pH range

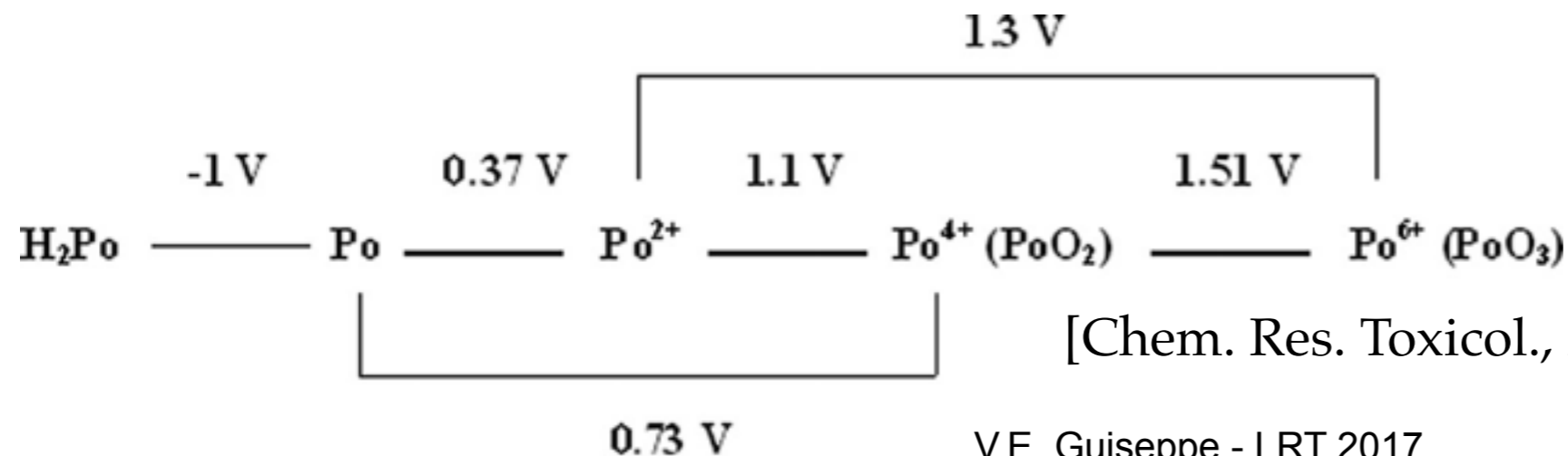
But, Po can redeposit or plate-out on the sample

At low pH, Po can exist in a stable ion state

Favors staying in solution

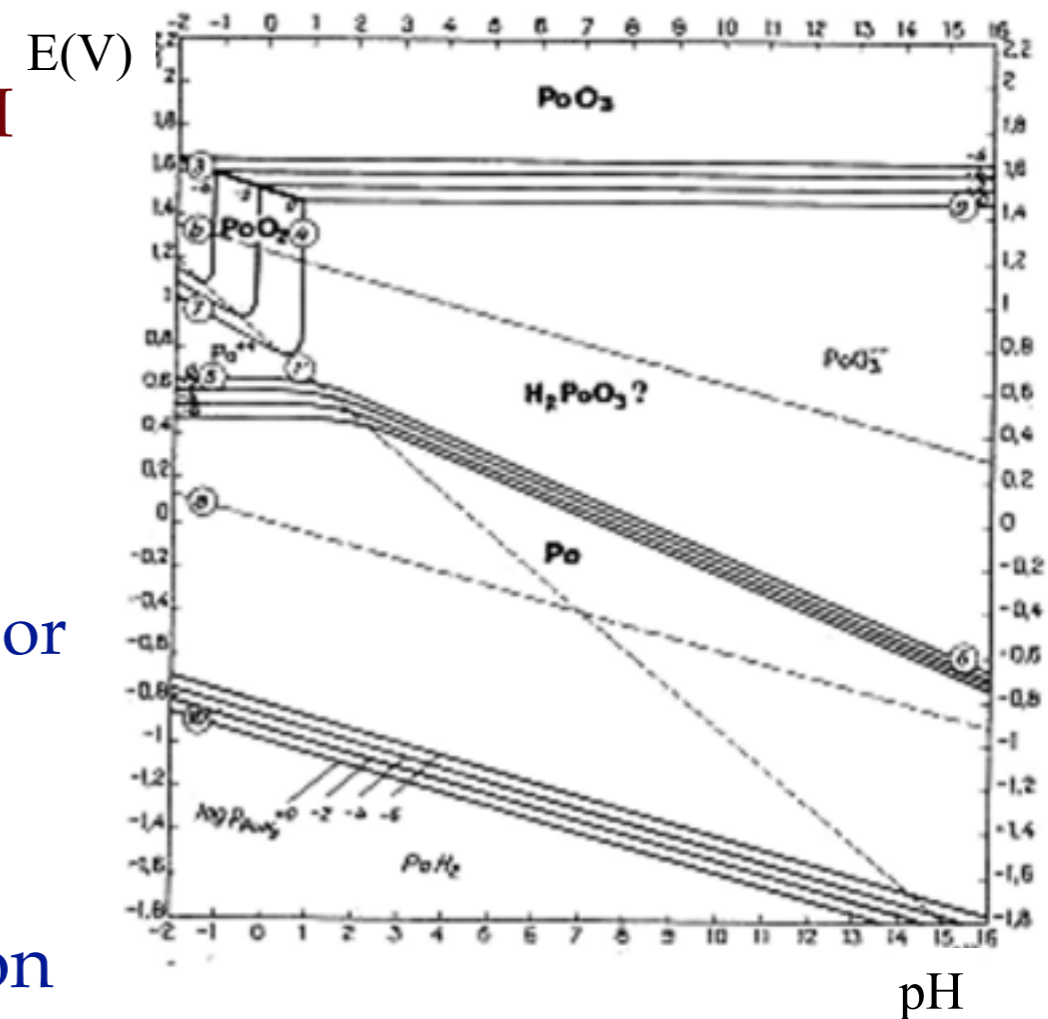
Forced through applying an oxidation potential or an oxidizing agent

Standard electrode potential of Po in acid solution



[Chem. Res. Toxicol., 2012, 25 (8), pp 1551–1564]

## Po Pourbaix Diagram



The  $\text{Po}^{4+}$  state is expected to be the most stable in solution



# Po Behavior

*The presence of an acidic solution is only the start.*

Requirements to keep Po off the sample surface:

Force Po into an ion state through oxidation, favorably  $\text{Po}^{4+}$

Sufficient solubility for the Po ions

Stability of ion state hinders redeposition

The substrate atoms (e.g. Cu) is being oxidized as well

Now there could be competition for the oxidizer (by applied potential or solution chemistry)

The kinetics of oxidation may be different between Po and the substrate atoms

**Sufficient exposure to the oxidizer may be the determining factor of effective Po removal**

Greater exposure can be accomplished several ways:

Agitation to make use of the full volume of solution, greater concentrations of the oxidizing agent, longer time, larger volumes of solution, etc.

# Po Behavior

*Why the mixed results for surface  $^{210}\text{Po}$  removal?*

Concentrated Nitric acid works well

Aggressive on all metals

Large amount of material removal

Electropolishing works well

Aggressive acids

Applied oxidizing potential

Large amount of material removal

PNNL method: acidified  $\text{H}_2\text{O}_2$  solution

The  $\text{H}_2\text{O}_2$  is the oxidizing agent

Modest material removal - important for tight dimensional tolerances on small parts

Range of starting Po surface concentration by over a factor of 10 (0.2 - 3 cpm)

Activity generated by:

- electrodeposition of  $^{209}\text{Po}$
- Exposure to Rn gas to deposit progeny and build-up  $^{210}\text{Po}$

General conclusion is that higher Po surface activity requires more aggressive cleaning

Mixed results reinforce the role played by kinetics and competing ion concentration or solubility

# Po Removal Stud

Focus on removal of  $^{210}\text{Po}$  from Cu

$^{210}\text{Pb}$  and  $^{210}\text{Bi}$  removal well demonstrated

Cu samples

50-mm diameter, 0.5 mm-thick Cu foil disks

Exposed to a 100 kBq radon source for ~ 1 month

Achieved an alpha count rate of 300 counts/day

Alpha Detector

Alpha spectrometer with an ion-implanted silicon detector.

Samples counted before and after treatment

Background of 6 counts/day

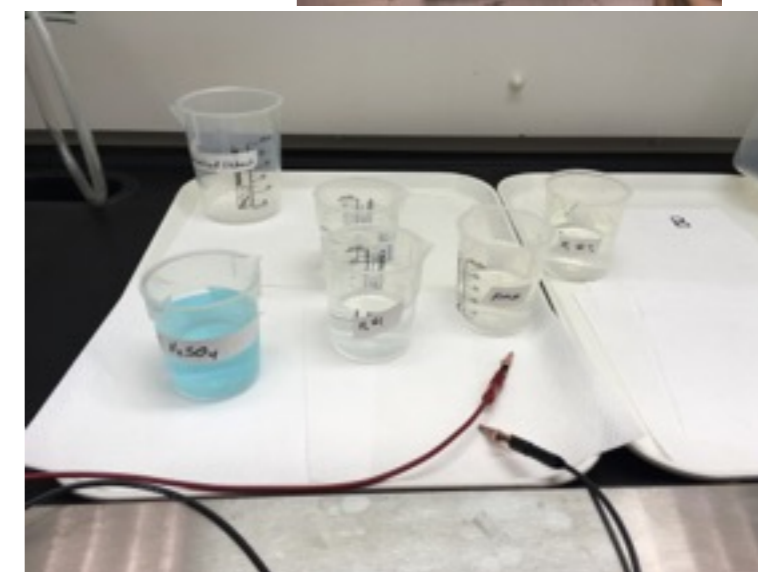
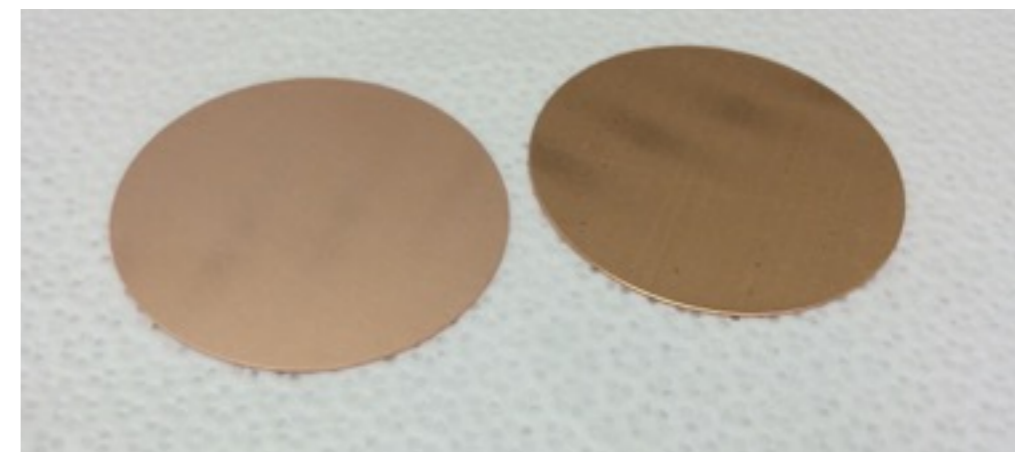
Goals:

Study a combination of oxidizing methods

Increased hydrogen peroxide concentration

Apply a cell potential in solutions

Vary the pH



# Po Removal Results

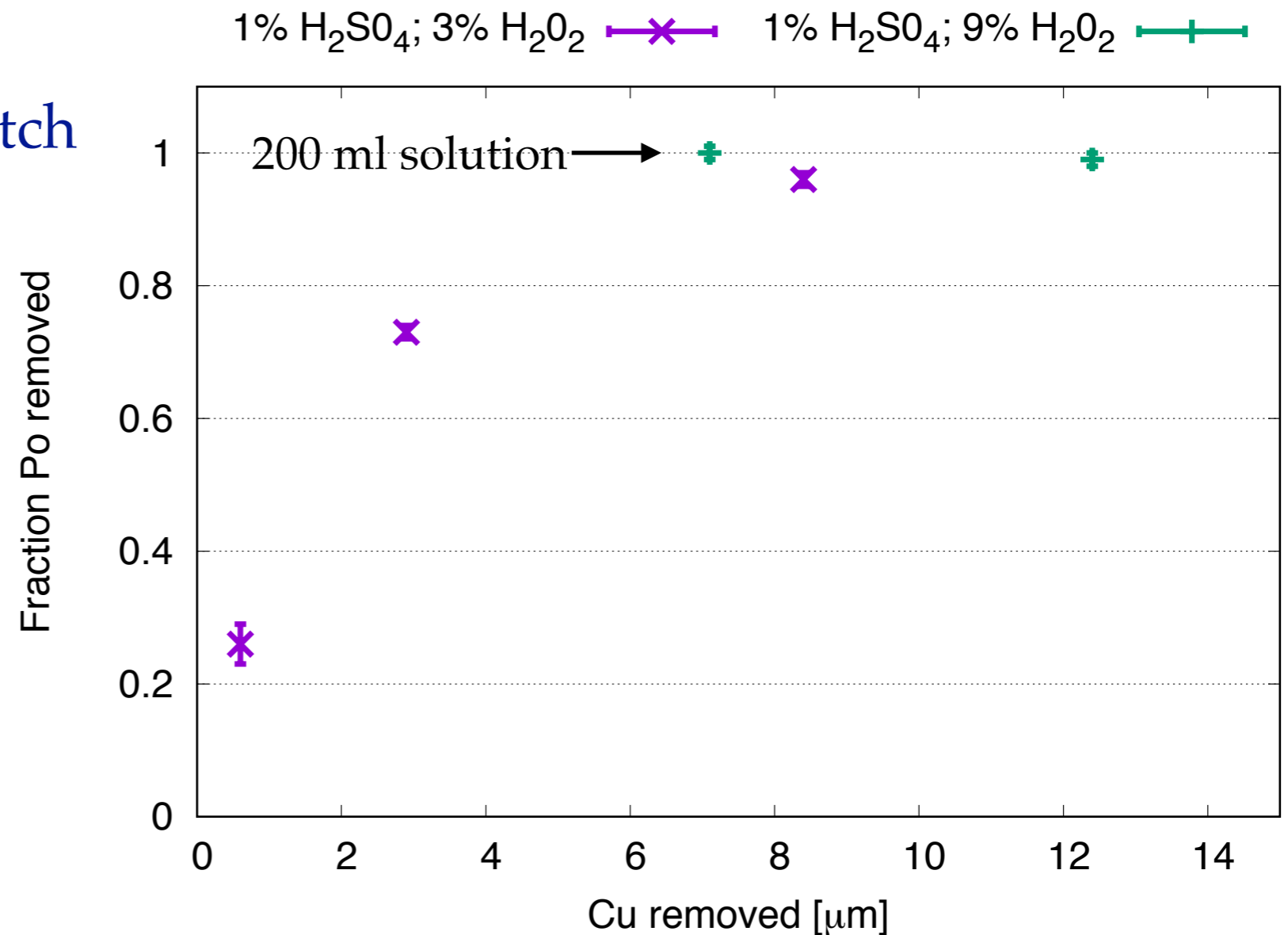
PNNL chemical solution

Samples agitated during the etch

100 ml solutions (one exception)

Adjusted the etching time and  $H_2O_2$  concentration (the exposure to the oxidizing agent)

General trend in surface Po removal independant of  $H_2O_2$  concentration



Should not generalize that the removal of Po achieved after sufficient depth of Cu removed

The implanted Po should exist <0.05 μm of depth

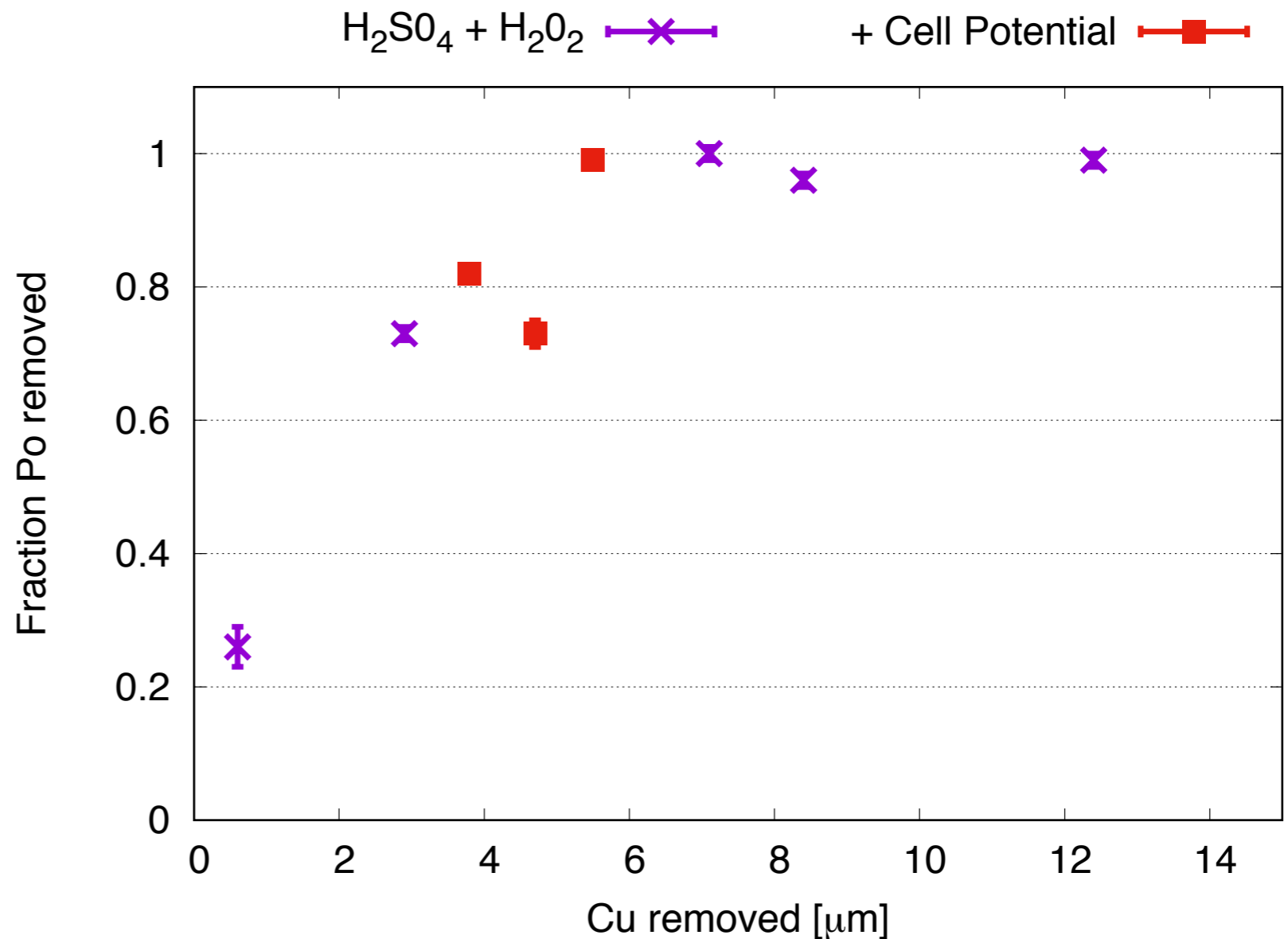
It's *not* the etch depth that alone determines the efficiency to remove Po

# Po Removal Results

PNNL chemical solution  
with a cell potential

Goal was to see if the cell  
potential increased the  
oxidation of Po

Can see that is not the case, no  
added benefit observed



Though the general trend is to improve Po removal, there exists some variability when only plotting against exposure

Next, look at initial Po surface concentration for effective treatments  
(where > 2 μm Cu removed)

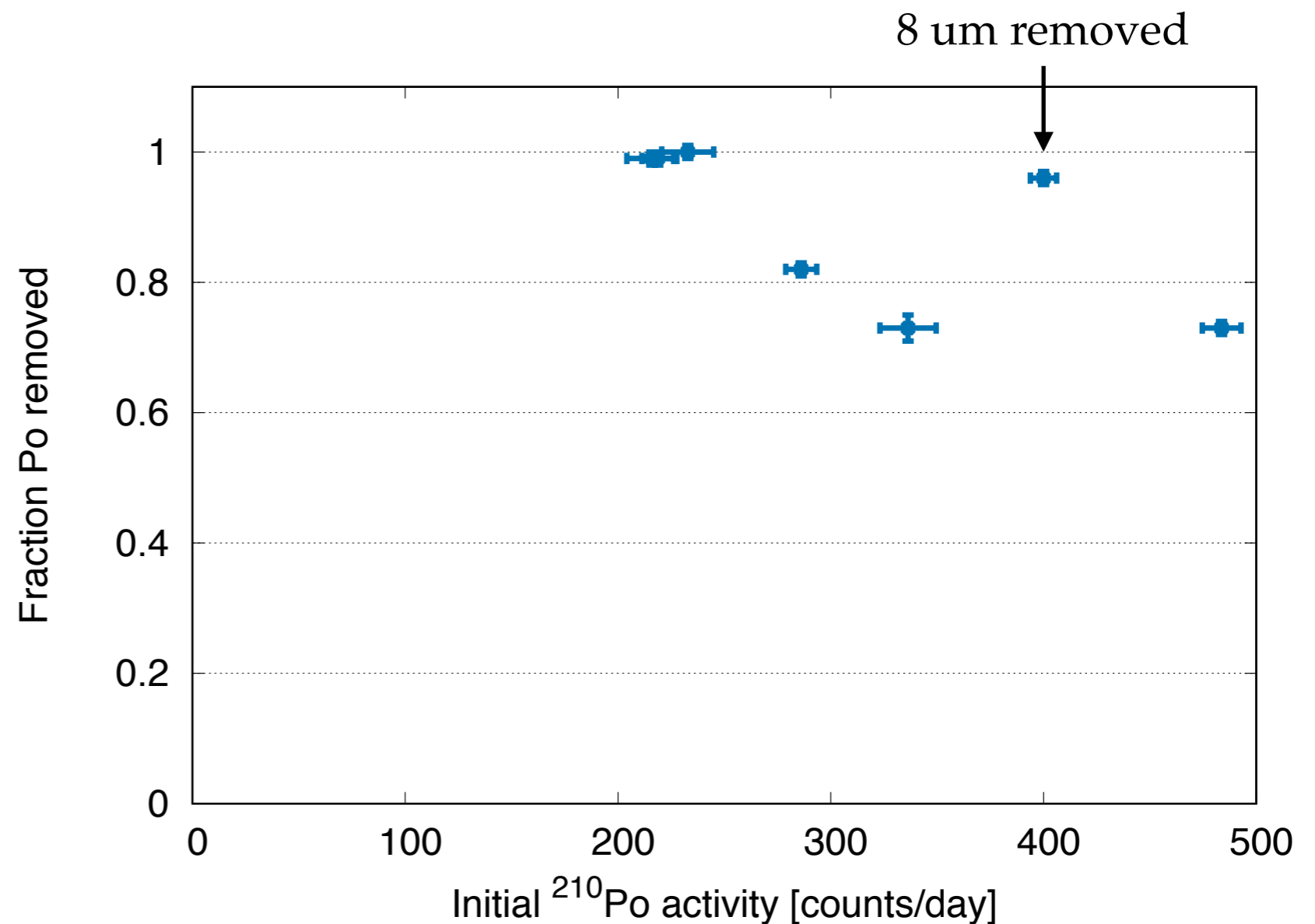
# Po Removal Results

PNNL chemical solution

Reduction as a function of initial Po activity

Lower Po concentration generally improves Po removal

Noted sample did have deep Cu etch suggesting greater solution exposure



Suggests the concentration of Po on the surface relates to exposure required in solution

When the exposure to the oxidizing agent was increased, the Po removal was optimized

# Po Removal Results

Alternate cleaning methods

Separate the peroxide oxidizing agent from cell potential

No peroxide

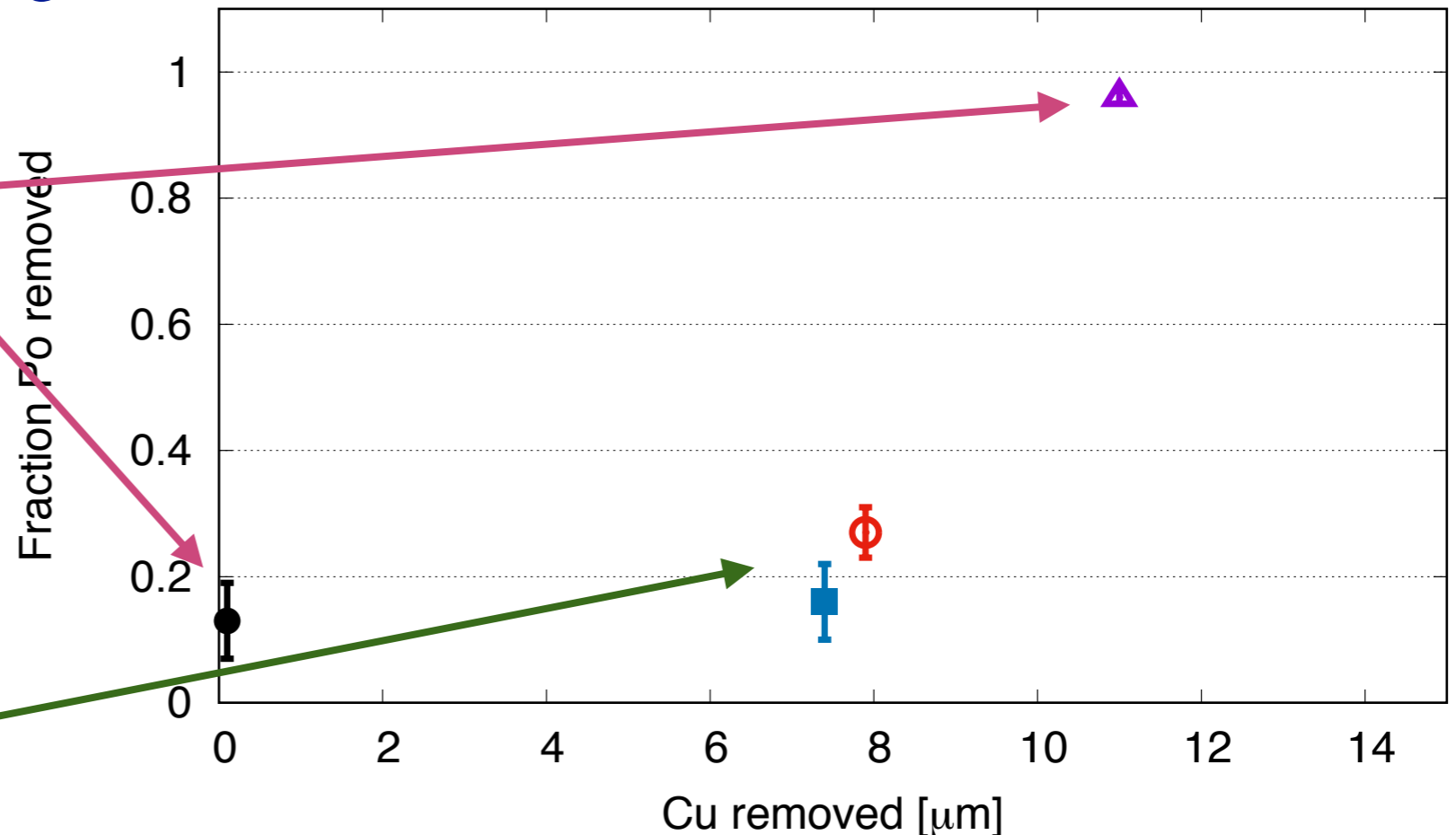
Cell potential required to remove Po and (and Cu)

Higher acidity in combination with peroxide

Not effective at removing Po, marginal improvement with an applied potential

Have a competition between Po and Cu, advantage to Cu with a lower oxidation potential

1M H<sub>2</sub>SO<sub>4</sub>; 6% H<sub>2</sub>O<sub>2</sub> ■  
1M H<sub>2</sub>SO<sub>4</sub>; 6% H<sub>2</sub>O<sub>2</sub> with cell potential ○  
6M H<sub>2</sub>SO<sub>4</sub> ●  
6M H<sub>2</sub>SO<sub>4</sub> with cell potential ▲



A cell potential alone can oxidize Po in an acidic environment - similar to standard electropolishing

No obvious advantage of applying a potential when an oxidizing agent is present

# Outlook

Rich history of studying radon progeny deposition and plate out

Likewise, successful studies that demonstrate methods to remove radon progeny from surfaces, including problematic  $^{210}\text{Po}$

Next generation experiments will have even stronger demands for cleaning Rn progeny surface contamination

Desirable to use methods that provide efficient removal and ease of implementation

Several factors that determine if the problematic  $^{210}\text{Po}$  will stay in solution during cleaning and be removed from a surface

Oxidizing the Po should keep it in solution and prevent redeposition

Oxidation can be achieved by a oxidizing agent or an applied potential in the right environment

The PNNL method is capable of efficiently removing Po from Cu

Need sufficient exposure to the oxidizing agent, especially when higher Po surface concentration is present: agitation of samples: greater solution volume

Need further studies to better explore the effects of solubility and Po concentration on various substrates (i.e anode, witness plate, electrolyte)